



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicants: Vlad J. Novotny and Parvinder Dhillon

Assignee: Active Optical Networks, Inc.

Title: "MICRO-ELECTRO-MECHANICAL SWITCHING SYSTEM"

Serial No.: 10/035,829 Filed: 10/18/2001

Examiner: Stahl, Michael J. Tel: 571-272-2360

Docket No.: AO-666 Art Unit: 2874
[AONIP001C1]

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INFORMATION DISCLOSURE STATEMENT

Sir:

Pursuant to 37 C.F.R. §1.56, §1.97 and §1.98, Applicants bring the 16 documents listed on the enclosed forms PTO-1449 to the Examiner's attention in the above-captioned application. Citation of the listed documents shall not be construed as:

1. an admission that the documents are necessarily prior art with respect to the instant application;
2. a representation that a search has been made; or
3. an admission that the information cited is, or is considered to be, material to patentability as defined in §1.56(b).

I hereby certify that this correspondence is being deposited with the United States Postal Service via First Class Mail and is addressed to: Mail Stop: Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450.

4.19.64
Date

Laurie Moreno

Respectfully submitted,

Arthur J. Behiel
Attorney for Applicants
Reg. No. 39,603



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| U.S. Department of Commerce, Patent and Trademark Office | | Serial No.: 10/035,829 |
| | | Filing Date: 10/18/2001 |
| SUPPLEMENTAL INFORMATION DISCLOSURE STATEMENT BY APPLICANT | | First Named Inventor: Vlad J. Novotny |
| "Micro-Electro-Mechanical Switching System" | | Group Art Unit: 2874 |
| | | Examiner Name: Stahl, Michael J. |
| | | Attorney Docket No.: AO-666 AONIP001C1 |

U.S. Patent / Patent Publication Documents

| *Examiner Initial | | Document Number | Date | Name | Class | Subclass | Filing Date, If Appropriate |
|-------------------|---|--------------------|----------|-------------------|-------|----------|-----------------------------|
| | A | 6,028,689 | 02/22/00 | Michalicek et al. | 359 | 224 | |
| | B | 6,253,001 B1 | 06/26/01 | Hoen | 385 | 17 | |
| | C | 6,283,601 B1 | 09/04/01 | Hagelin et al. | 359 | 871 | |
| | D | 6,301,403 B1 | 10/09/01 | Heanue et al. | 385 | 18 | |
| | E | US 2002/0171327 A1 | 11/21/02 | Miller et al. | 310 | 309 | |

OTHER ART (Including Author, Title, Date, Pertinent Pages, Etc.)

| | | |
|--|---|--|
| | F | ELWENSPOEK, M. et al., "Silicon Micromachining." 1998 - Cambridge University Press. Cover page, pages 102-111, pages 160-161 and page 282. |
| | G | MALUF, NADIM, "An Introduction to Microelectromechanical Systems Engineering." 2000. Cover page, pages 6464-73 and pages 186-189. |
| | H | RAI-CHOUDHURY, P., "Handbook of Microlithography, Micromachining, and Microfabrication." 1997 - SPIE Optical Engineering Press. Pages 110-116 and pages 120-122. |
| | I | CONANT, ROBERT A. et al., "A Flat High-Frequency Scanning Micromirror." 2000 - Solid-State Sensor & Actuator Workshop, Hilton Head, SC. |
| | J | BEZUK, STEVE, PH.D., "Flip Chip Challenges." 02/00 - HD Magazine. 6 pages. |
| | K | CHEN, YIJIAN, "Control and Shape Design of an Electrically-Damped Comb Drive for Digital Switches." 2000 - MOEMS and Miniaturized Systems. Proceedings of SPIE Vol. 4178. Pages 387-394. |
| | L | DAWSON, J.M. et al., "MEMS Feedback Control Using Through-Wafer Optical Device Monitoring." September 2000 - Proc. Of SPIE Vol. 4178, MOEMS and Miniaturized Systems. |

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| Examiner | Date Considered |
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*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with your communication to applicant.



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|-------------------|---|-----------------|------|------|-------|----------|-----------------------------|
| | M | | | | | | |
| | N | | | | | | |
| | O | | | | | | |
| | P | | | | | | |
| | Q | | | | | | |

OTHER ART (Including Author, Title, Date, Pertinent Pages, Etc.)

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|---|--|
| R | LEE, SANGWOO, et al., "The Surface/Bulk Micromachining (SBM) Process: A New Method for Fabricating Released MEMS in Single Crystal Silicon." December 1999. Journal of Microelectromechanical Systems, Vol. 8, No. 4. Pages 409-416. |
| S | MILANOVIC, VELJKO, "Optical MEMS for Optical Communications - Trends and Developments." 12/01. Adriatic Research Institute. Pages 2-6. |
| T | NEE, JOCELYN T. et al., "Lightwave, Optically Flat Micromirrors for Fast Beam Steering." Presented at IEEE/LEOS Optical MEMS August 2000 Conference in Kauai, Hawaii. 2 pages. |
| U | TIEN, NORMAN C. et al., "MEMS Actuators for Silicon Micro-Optical Elements." 2000 - Proceedings of SPIE Vol. 4178. Pages 256-267. |
| V | |
| W | |
| X | |

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|----------|-----------------|
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